

10/544159

Substitute for Form 1449/PTO		<b>Complete if Known</b>	
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use as many sheets as necessary)		Application Number	
		Filing Date	
		First Named Inventor	Peter STAUSS
		Art Unit	
		Examiner Name	
Sheet 1 of 2	Attorney Docket Number	5367-191PUS	

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind-Code <sup>2</sup> (if known)			
		US-4,749,840 A	06/07/1988	Piwczyk	
		US-6,136,141 A	10/24/2000	Akkashian et al.	
		US-5,326,424 A	07/05/1994	Doll et al.	
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FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages	T <sup>6</sup>
		Country Code <sup>3</sup> Number <sup>4</sup> Kind-Code <sup>5</sup> (if known)				
		WO 98/14986	04/09/1998	Ambacher		
		JP 2000 196197	11/17/2000	Xerox Corp.		Abstract
		EP 0 247 331 A	12/02/1987	IBM		
		DE 100 56 645 A1	09/13/2001	Dadgar		
		DE 196 40 594 A1	04/02/1998	Siemens AG		
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		WO 95/03628	02/02/1995	Karg		
		DE 43 24 318 C1	01/12/1995	Siemens AG		
		DE 198 21 544 A1	12/16/1999	Lorenzen et al.		Abstract
		DE 197 06 279 A1	08/20/1998	Siemens AG		
Examiner Signature	/Howard Weiss/			Date Considered	06/05/2008	

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NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
		Wong et al., "Structural and Optical Quality of GaN/Metal/ SI Heterostructures Fabricated by Excimer Laser Lift-Off", Applied Physics Letters, American Institute of Physics, New York, Vol.. 75, No. 13, September 1999	
		Toet et al., "Thin-Film Transistors Fabricated in Printed Silicon", Japanese Journal of Applied Physics", Vol. 38, No. 10A, pp. L1149 -L1152, October 1999	
		Angelis, et al., "Electrical and Noise Properties of Thin-Film Transistors on Very Thin Excimer Laser Annealed Polycrystalline Silicone Films", Applied Physics Letters, American Institute of Physics, New York, Vol.. 74, No. 24, pp. 3684 - 3686, June 1999	
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		C.T. Angelis, et al., "Effect of excimer laser annealing on the structural and electrical properties of polycrystalline silicon thin-film transistors", Journal of Applied Physics, Vol. 86, No. 8, pp. 4600-4606, October 1999	
		Yong-Feng Lu et al., "Excimer-Laser Removal of SiO <sub>2</sub> Patterns from GaAs Substrates", Jpn. Journal of Applied Physics, Vol. 33, No. 3A, Part 2, pp. L324-L327	
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		Laser Beam Homogenizer, Laser-Laboratorium Gottingen e.v., Technisches Datenblatt, 1995	
		I. Schnitzer et al., "30% external quantum efficiency from surface textured, thin-film-light-emitting diodes", Appl. Phys. Lett. Vol. 63, No. 16, pp. 2174-2176, October 1993	
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